



# Characterization and modelling of piezoelectric semiconducting nanowires and transducers



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## I. Introduction

### Piezoelectric materials

## II. Characterization of piezoelectric nanowires

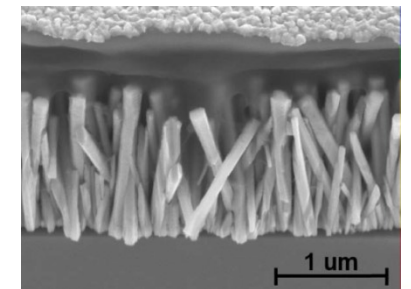
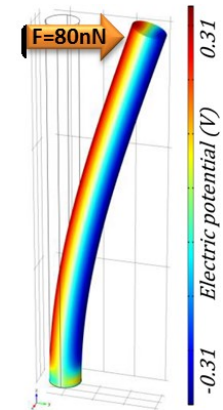
### AFM techniques

## III. Modeling of piezo-NWs and nanogenerators

### Comparison vs. experiments

### Surface traps and their effect on device performance

## V. Conclusions and perspectives

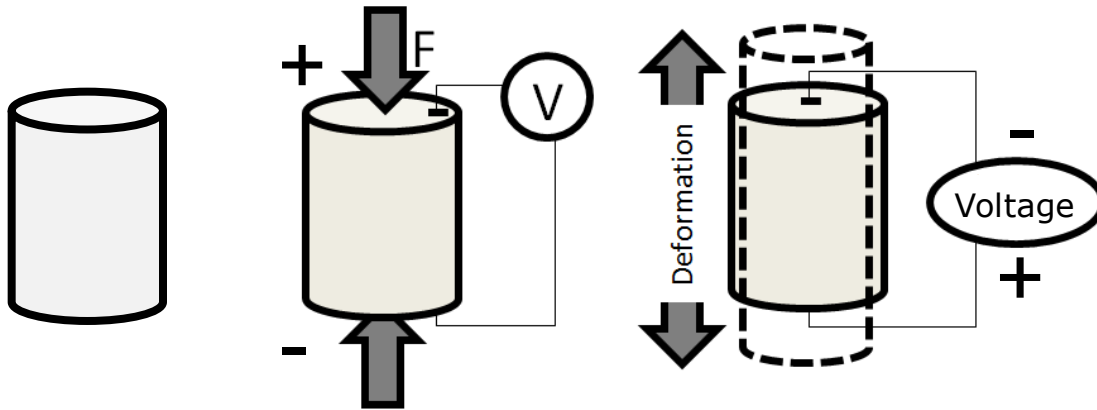


# Introduction (1/4)

## Piezoelectricity

### What is the piezoelectric effect?

Materials with non centro-symmetric crystal structure  
(ex: Quartz, PZT, GaN, ZnO, AlN, etc)



1) Direct effect : Force  $\rightarrow$  Electric field

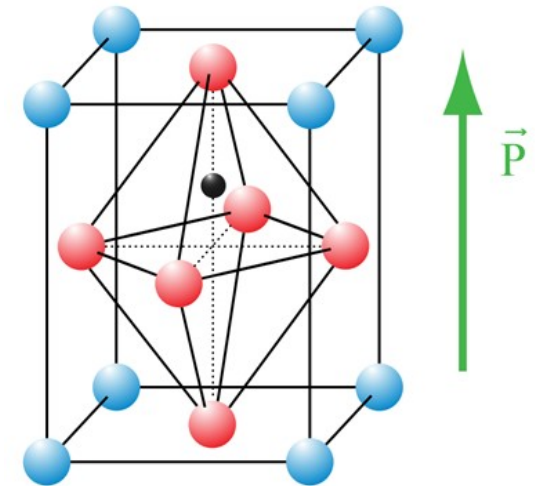
**Sensors and energy harvesters**

2) Reverse effect : Electric field  $\rightarrow$  Strain

**Actuators and haptic devices**

PZT crystal structure

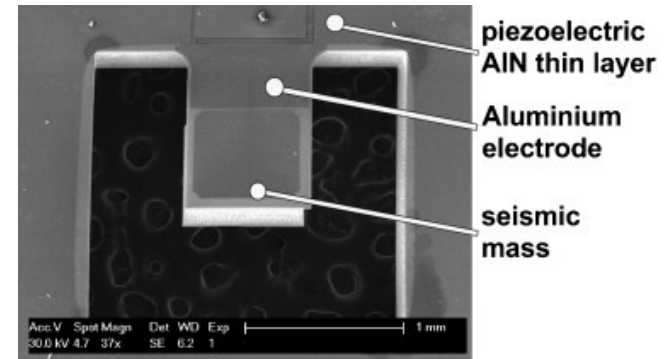
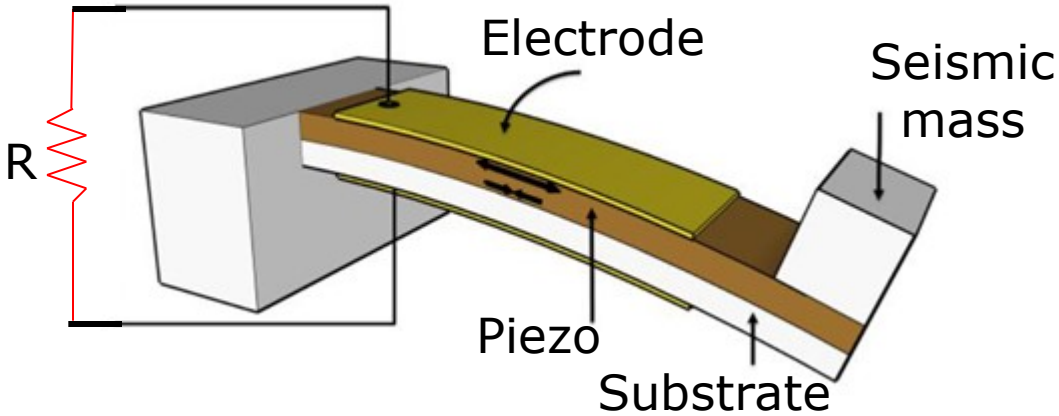
$\bullet$  Pb<sup>2+</sup>  $\bullet$  O<sup>2-</sup>  $\bullet$  Ti<sup>4+</sup>, Zr<sup>4+</sup>



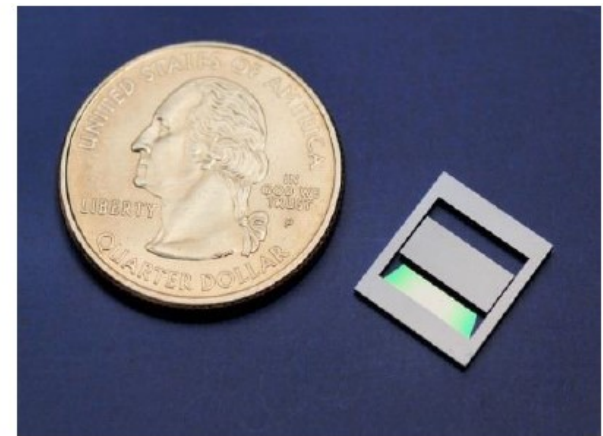
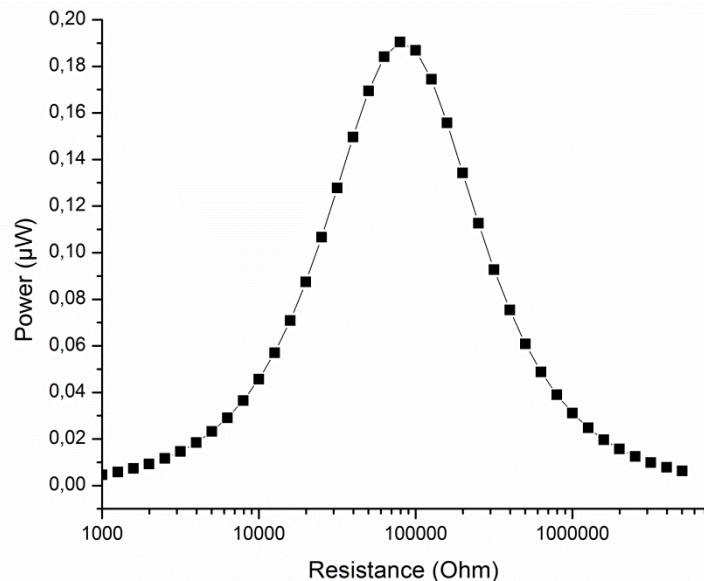
## Piezoelectric materials for EH

Basic resonant structure

Uses mainly thin films (AlN, ZnO, PZT)



Marzenki et al. S&A 2008 (TIMA)



Microgen (USA) AlN based commercial MEMS harvesters

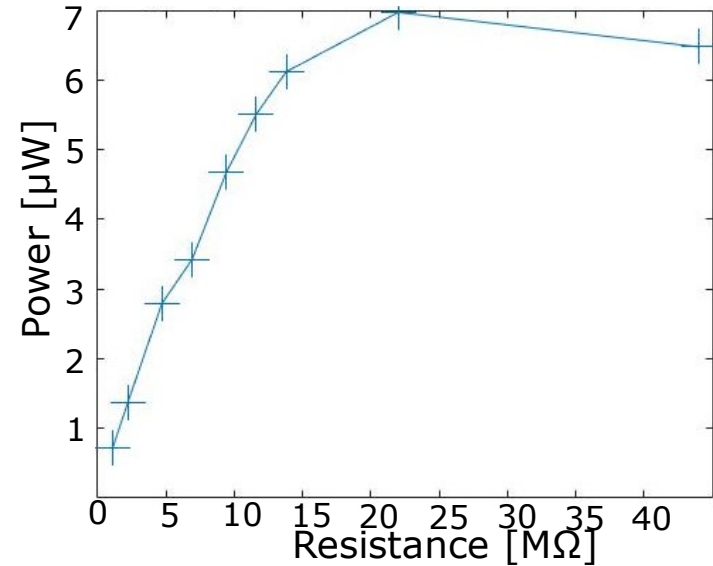


## Piezoelectric materials for EH

Flexible non-resonant structures



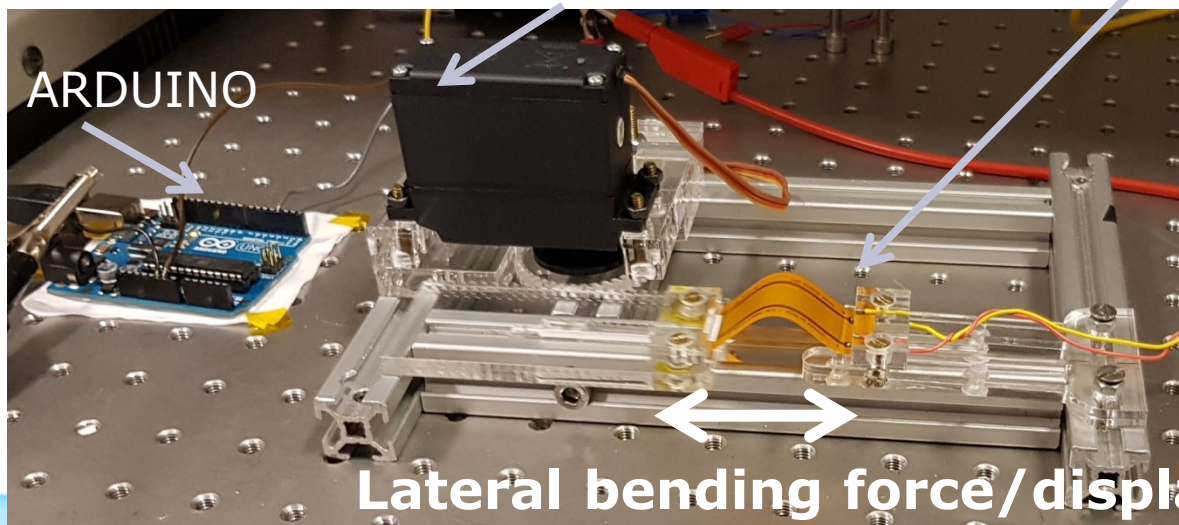
Measurement example on a TE Connectivity device (@0.3Hz and 3mm of lateral displacement)



Characterization set-up

Servo-Motor

Flexible piezoelectric device



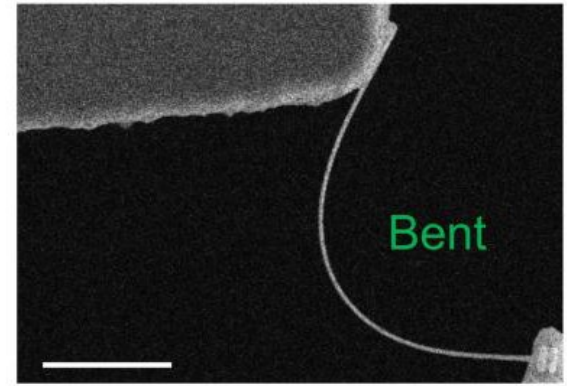
Lateral bending force/displacement

## Nanowires and nanocomposites

### Advantages of piezoelectric nanowires? ( $\sim 10\text{nm}$ wide, $> 500\text{nm}$ long)

- Higher flexibility
- High sensitivity to small forces
- Enhanced piezoelectric properties

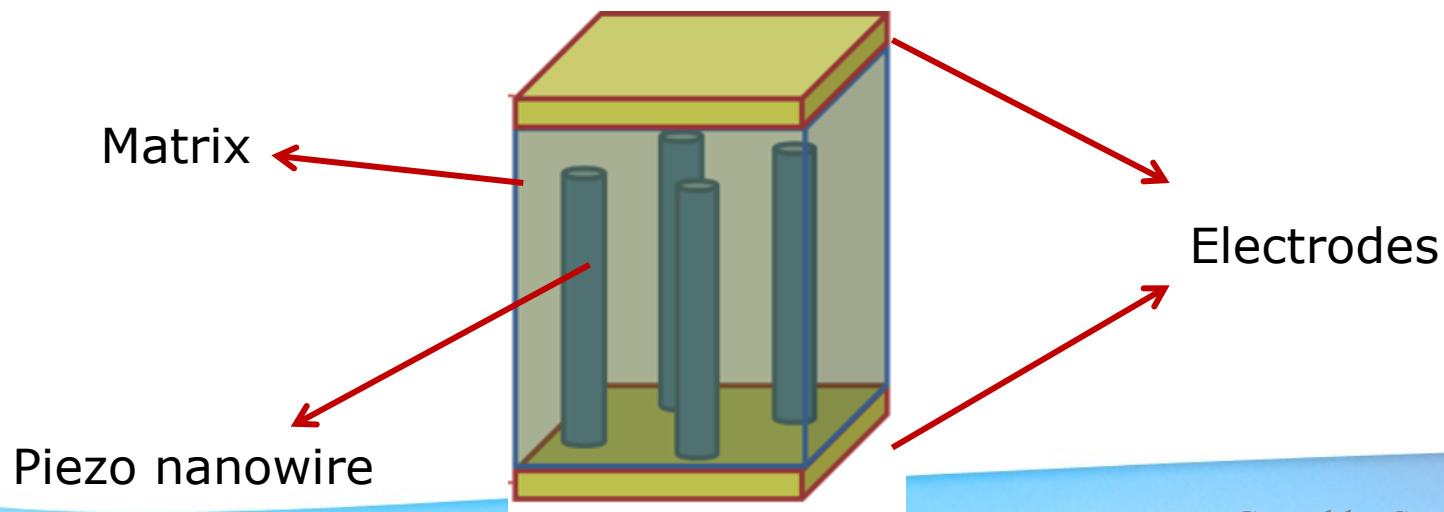
M-H. Zhao et al., Nanoletters 4, 2004



ZnO nanowires

G. Cheng et al., Nature Nanotech. , 2015

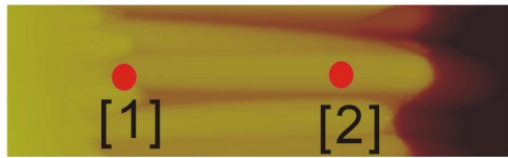
### Piezoelectric Nanocomposites (NWs immersed in a dielectric)



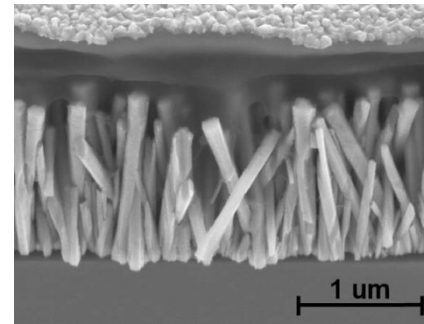
# Our activities on piezoelectric NWs and piezo devices

NWs individual characterization

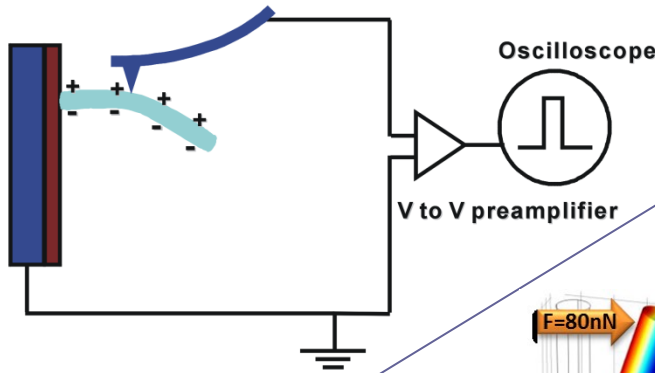
NW integration into devices and characterization



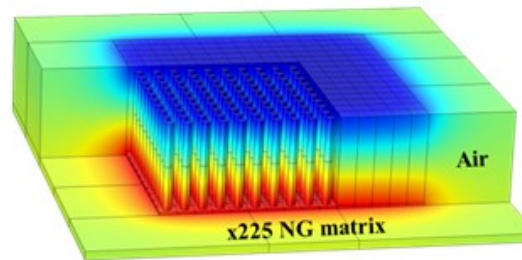
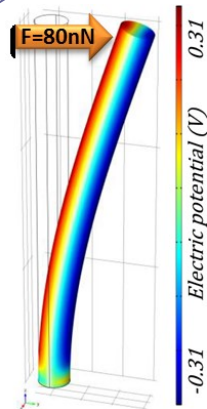
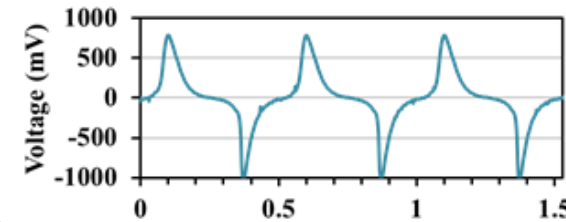
AFM techniques



VING nanogenerator integration



Modeling



FEM and analytical models



# **Individual nanowire characterization**

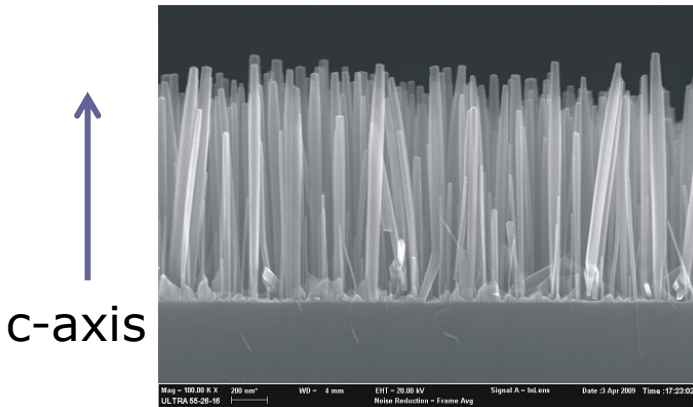
## **AFM techniques and applications to sensing**



# Individual NW characterization

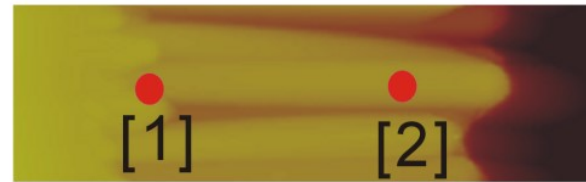
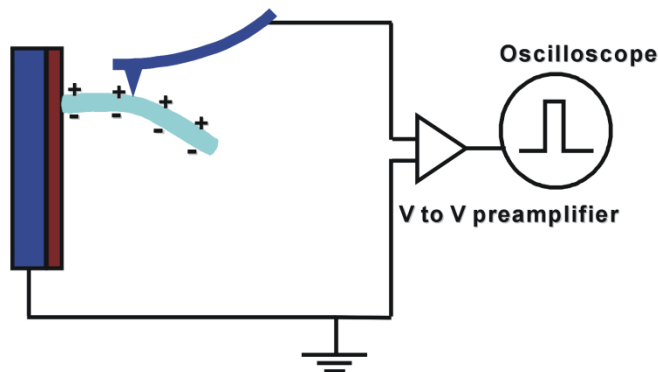
## Electromechanical characterization

Near field characterization techniques



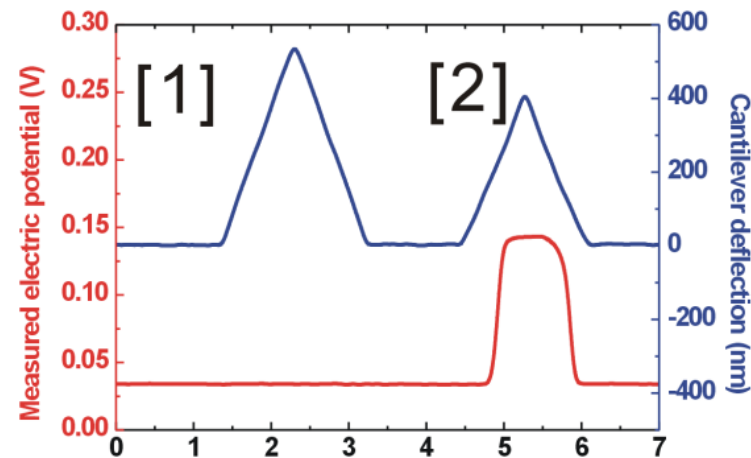
GaN NW (30nm wide, 1 $\mu$ m long)  
Grown by MBE on AlN/Si substrate.

R. Songmuang et al., APL 91 2007



Selection of specific locations on the NW

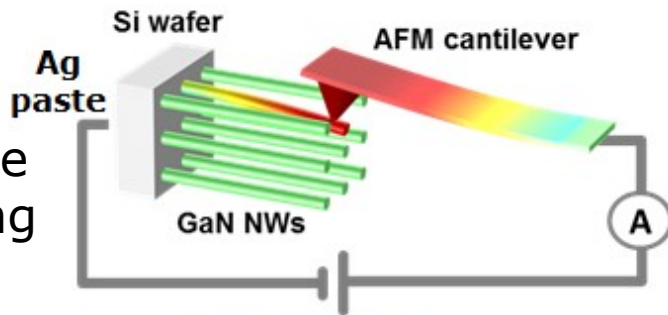
*Collab.  
Neel I.  
and  
LTM labs  
(PhD X. Xu and  
A. Potié)*



X. Xu, L. Montès et al., Nanotechnology 22 (2011)

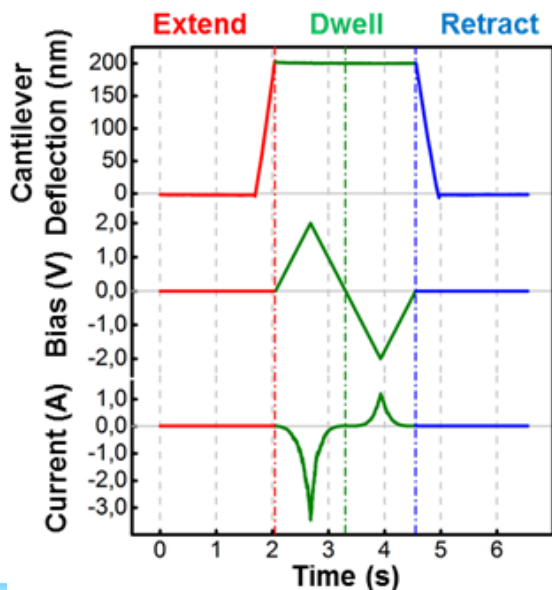
# Individual NW characterization

## Mechanical sensor – piezotronic effect



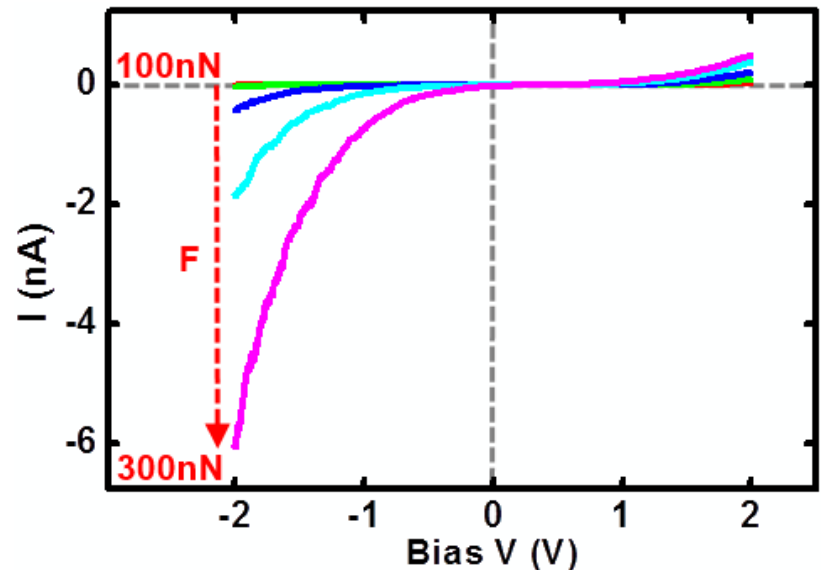
60nm wide  
1.5 $\mu$ m long

*Collab.  
Neel I.  
and  
GeorgiaTEC*



### Experimental measurement:

- Current  $I$  through the Schottky junction GaN NW / Pt AFM tip
- I-V as function of  $F$



*PhD R. Hinchet*

Y. Zhou, R. Hinchet et al., Adv Mat, 2012

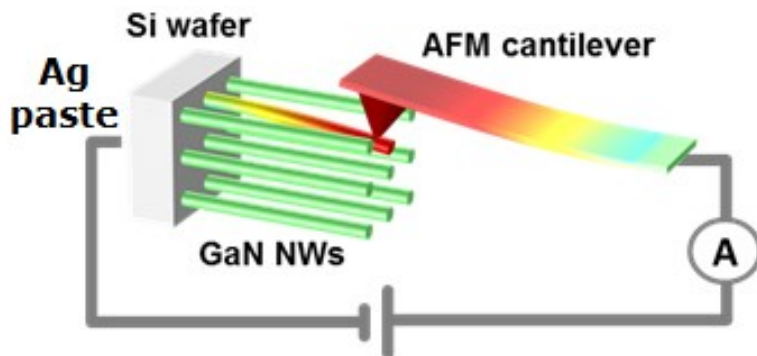
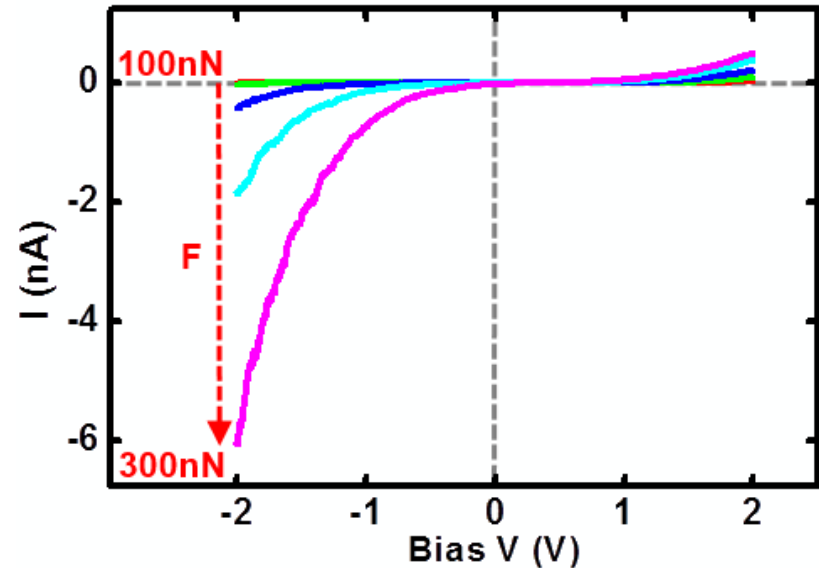
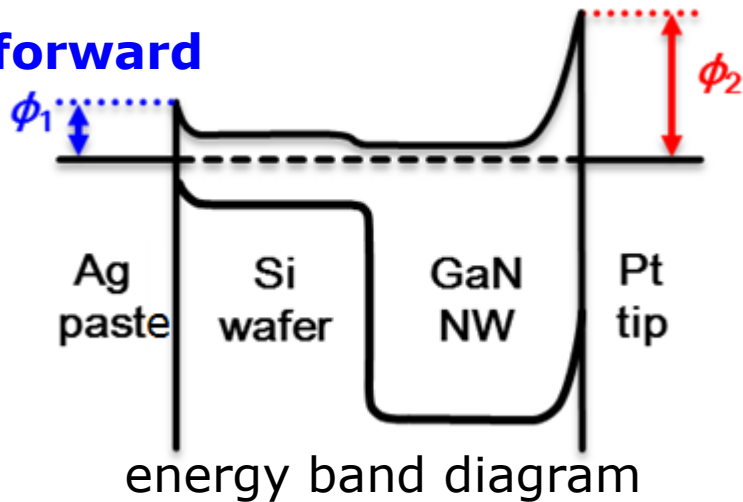
# Individual NW characterization

## Mechanical sensor – what's behind?

Piezoelectric effect on Schottky diode:

**reverse**

**forward**



*PhD R. Hinchet*

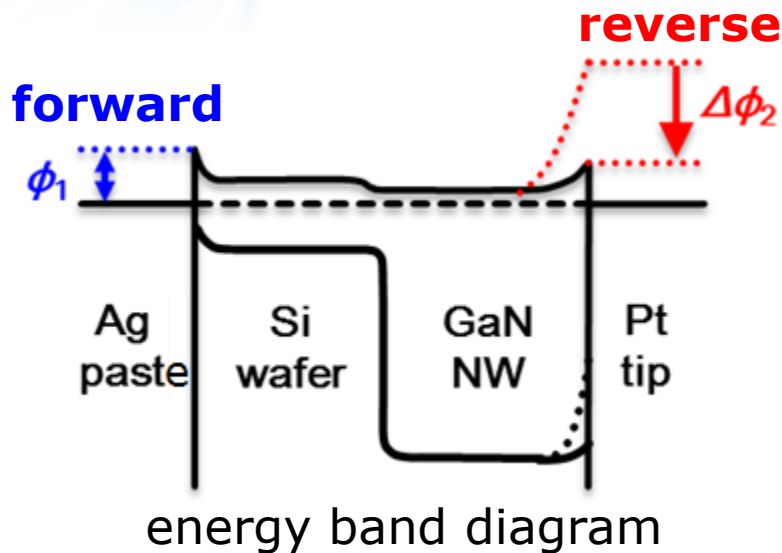
Y. Zhou, R. Hinchet et al., *Adv Mat*, 2012

Grenoble, September 11 2019

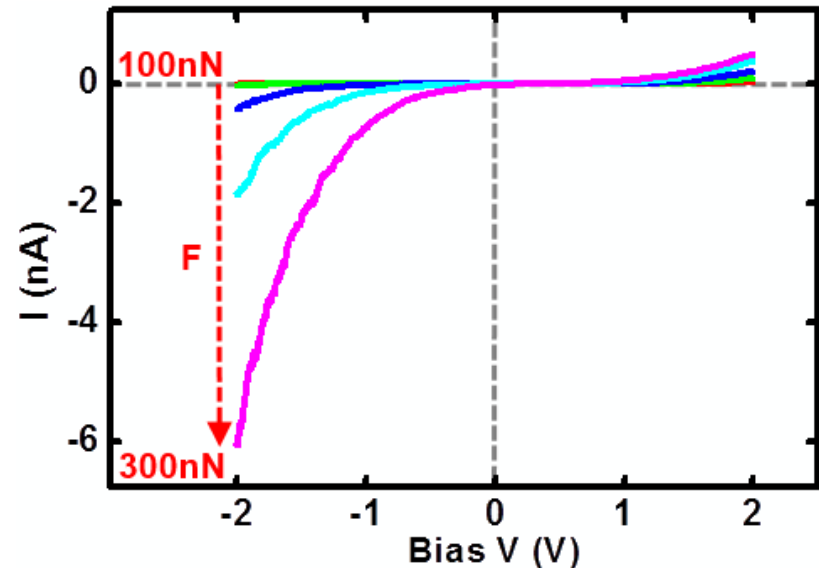
# Individual NW characterization

## Mechanical sensor – what's behind?

Piezoelectric effect on Schottky diode:



- Local potential  $\searrow$  barrier height
- $\nearrow$  current through Schottky



- High sensitivity: 1.2 In(A)/nN
- Resolution: better than 16nN
- Response time:  $\tau < 5\text{ms}$  (200Hz)

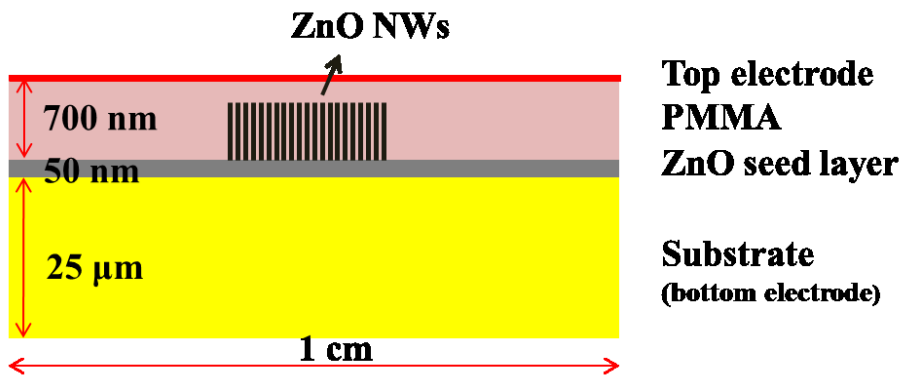
Y. Zhou, R. Hinchet et al., Adv Mat, 2012





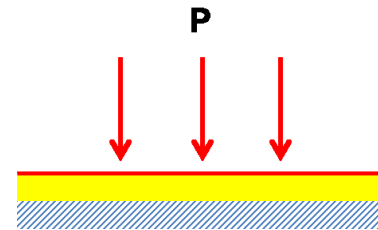
# Devices modeling

VING sandwiched by two electrodes  
(composite material)

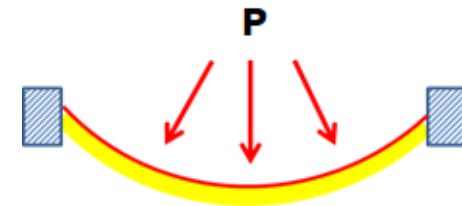


Working modes

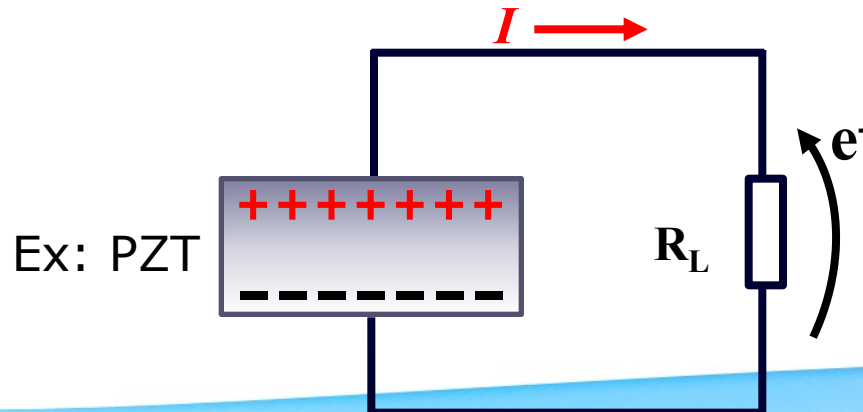
Compression



Bending



Basic models : Insulating piezoelectric material

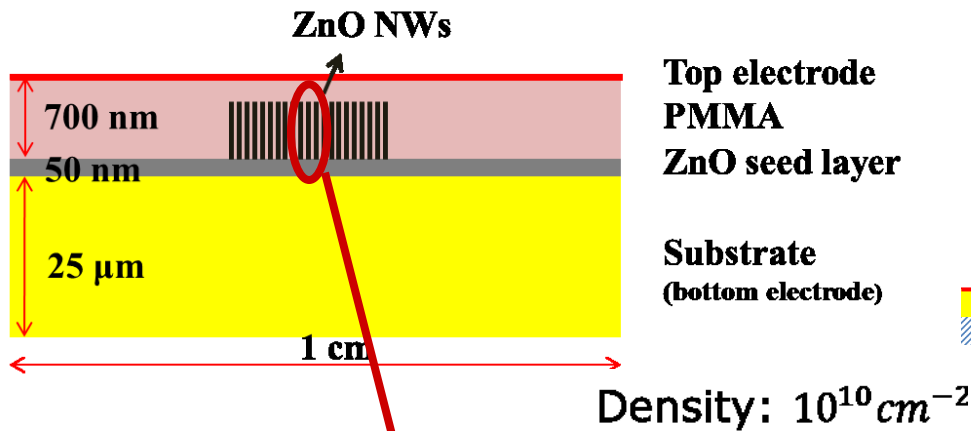


# Our models : VING based on ZnO NWs

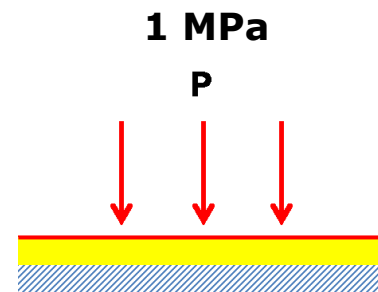
## 3D unit cell approach

VING sandwiched by two electrodes

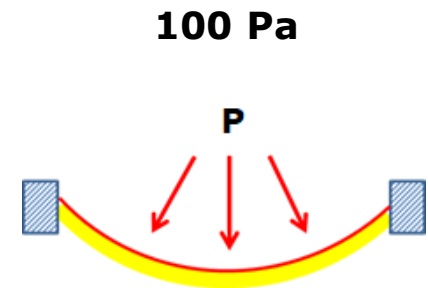
Working modes



**Compression**



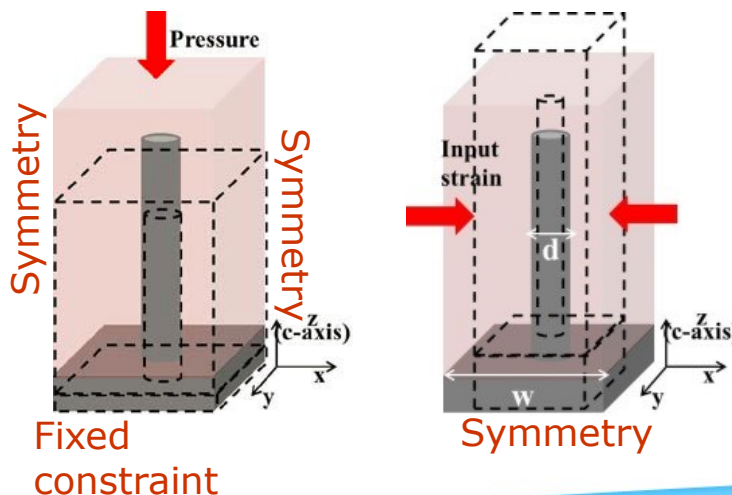
**Bending**



**Mechanical**

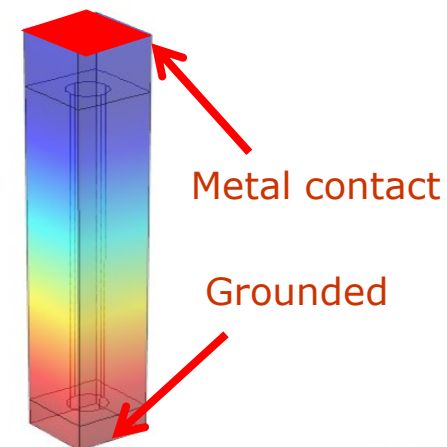
Linear elasticity  
Bulk properties

$d = 50 \text{ nm}$   
 $L = 600 \text{ nm}$   
Ratio =  $d/w$   
(density)



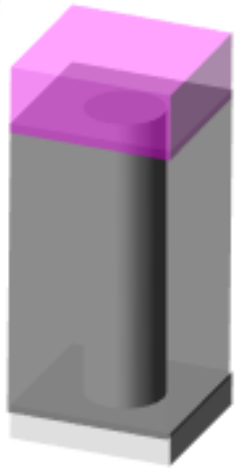
**Electrical**

No Semi-conducting properties



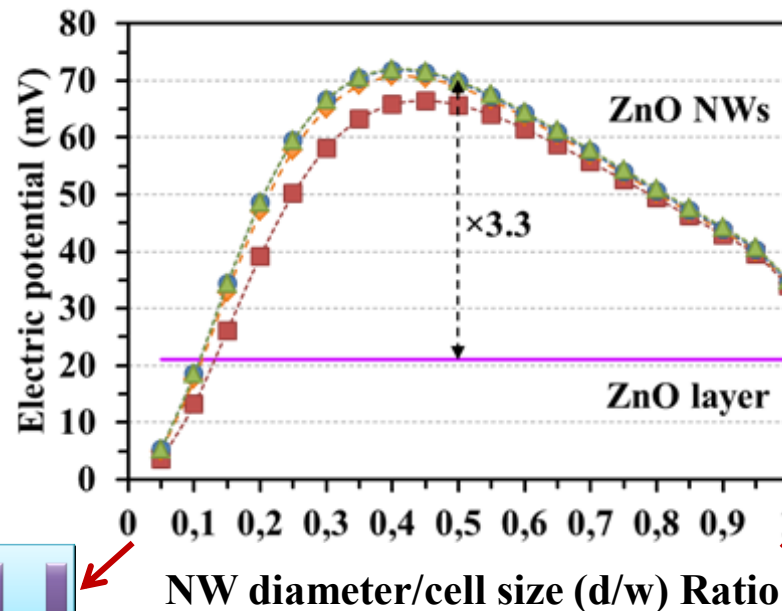
# Our models : VING based on ZnO NWs

## An example in compression mode



PMMA matrix  
Top layer  
varies

Material	PMMA	SiO <sub>2</sub>	Si <sub>3</sub> N <sub>4</sub>	Al <sub>2</sub> O <sub>3</sub>
	□	○	△	×
E (GPa)	3	70	250	400
$\kappa_{33}$	3.9	4.2	9.7	5.7



R. Hinchet et al.,  
Adv. Funct. Mater. 2014

R. Tao et al.,  
Nano Energy 2015



NW diameter/cell size (d/w) Ratio



Several ways to optimize the performance in compression mode:

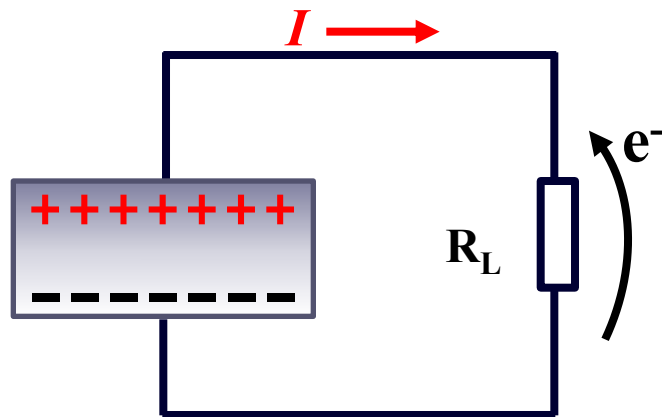
- Use a medium range of density
- Use hard materials as a top dielectric layer



## ZnO as semiconductor :

- Unintentionally doped in the growth ( $\sim 10^{16} - 10^{17} \text{ cm}^{-3}$ )

### Insulating piezoelectric material

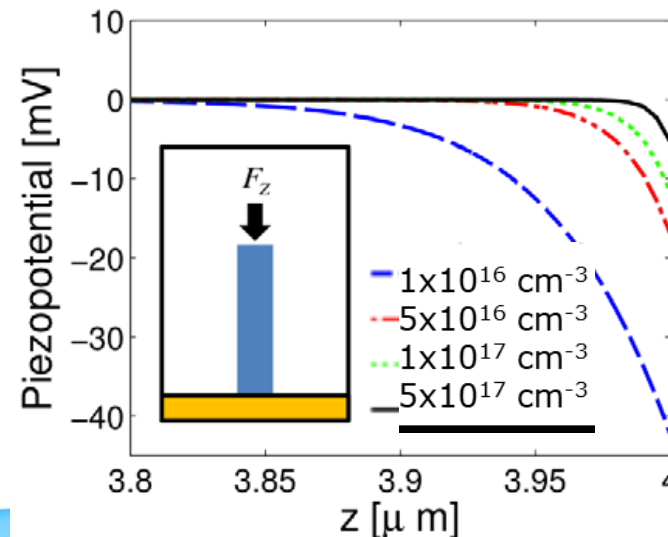
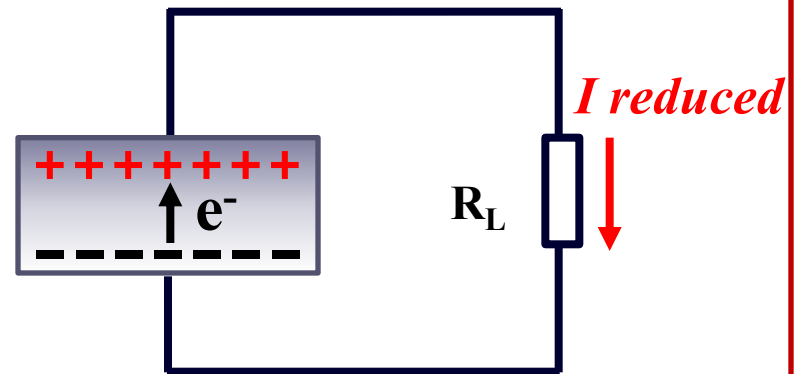


If an individual ZnO NW is n-doped,

- Depleted region at the top
- Length independent for NW longer than 200 nm
- Low output , heavily screened with higher doping

### With free carriers

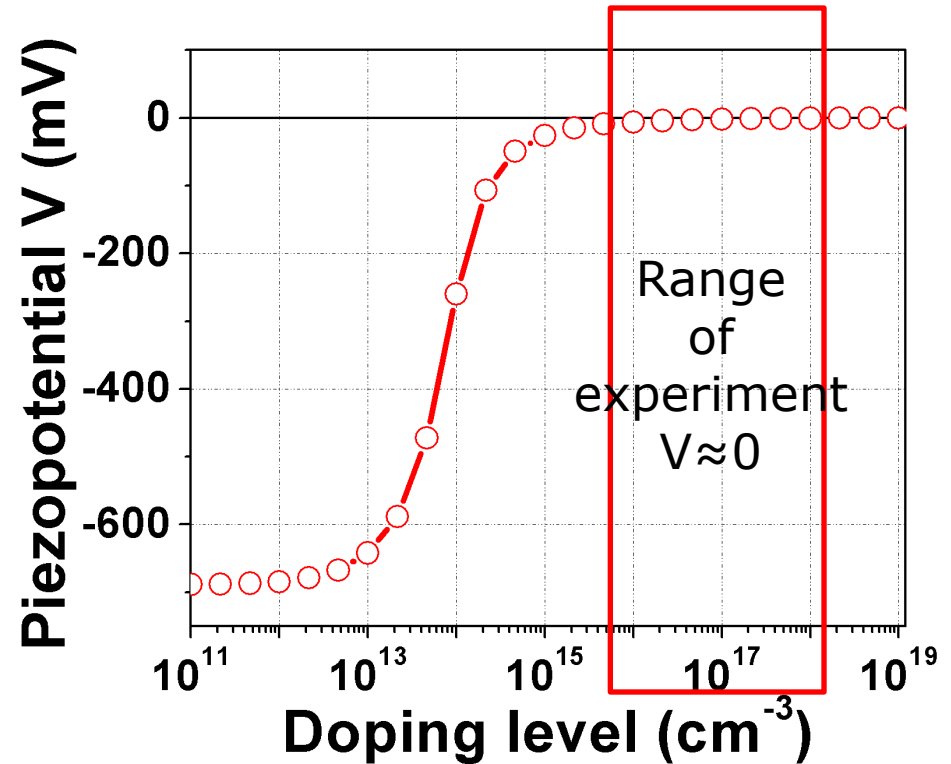
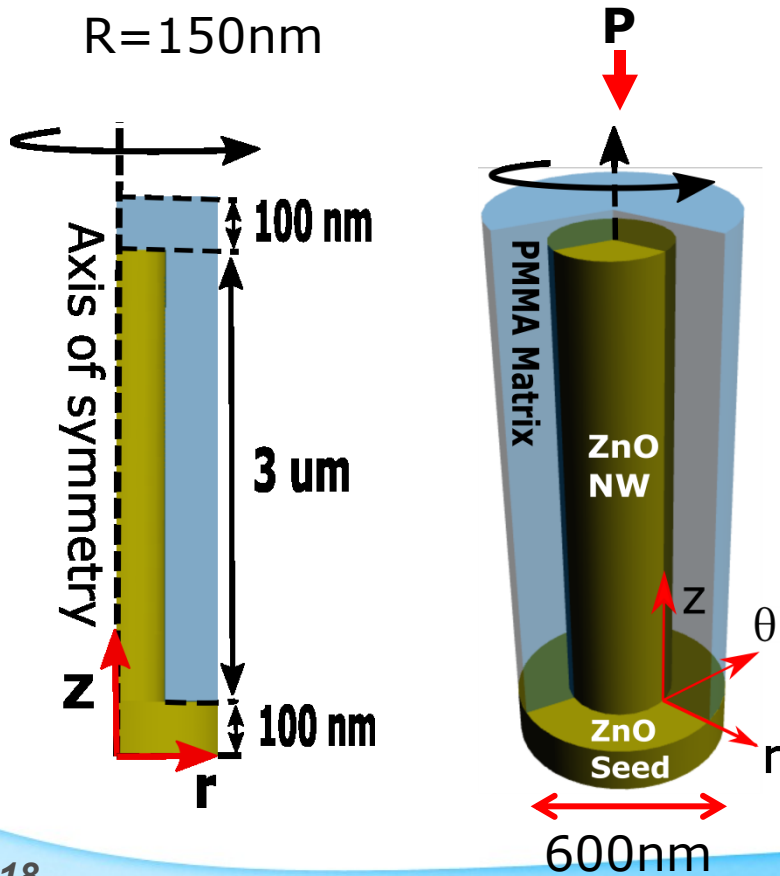
Semiconductor (GaN, ZnO...)



R=150nm  
L= 4μm

## 2D axisymmetric approach : VING based in ZnO NWs immersed in PMMA

- **Unit cell :**
- ZnO/PMMA composite

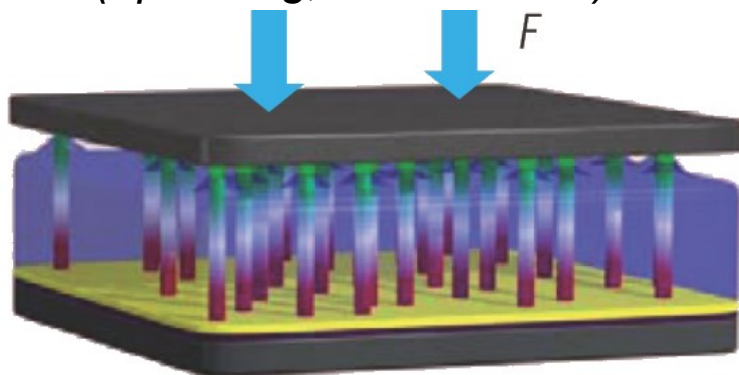


- Close to **0V** at doping  **$10^{15} \text{cm}^{-3}$**

# VING experimental results

How can we explain these results from a theoretical point of view ?

ZnO NWs integrated into Si  
(4 $\mu$ m long, 300nm wide)



96mV  
8.9nA/cm<sup>2</sup>

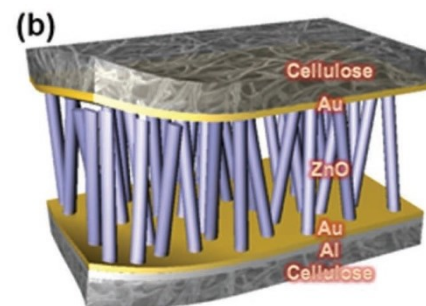
S. Xu et al.,  
Nature Nanotech., 2010

ZnO NWs (2 $\mu$ m long, 150nm wide)



Y. Hu et al., Adv. Mat., 2011

ZnO NWs integrated into paper



2 $\mu$ A/cm<sup>2</sup>  
75mV

K-H. Kim et al., Small, 2011

Sungkyunkwan University, Republic of Korea

Grenoble, September 11 2019

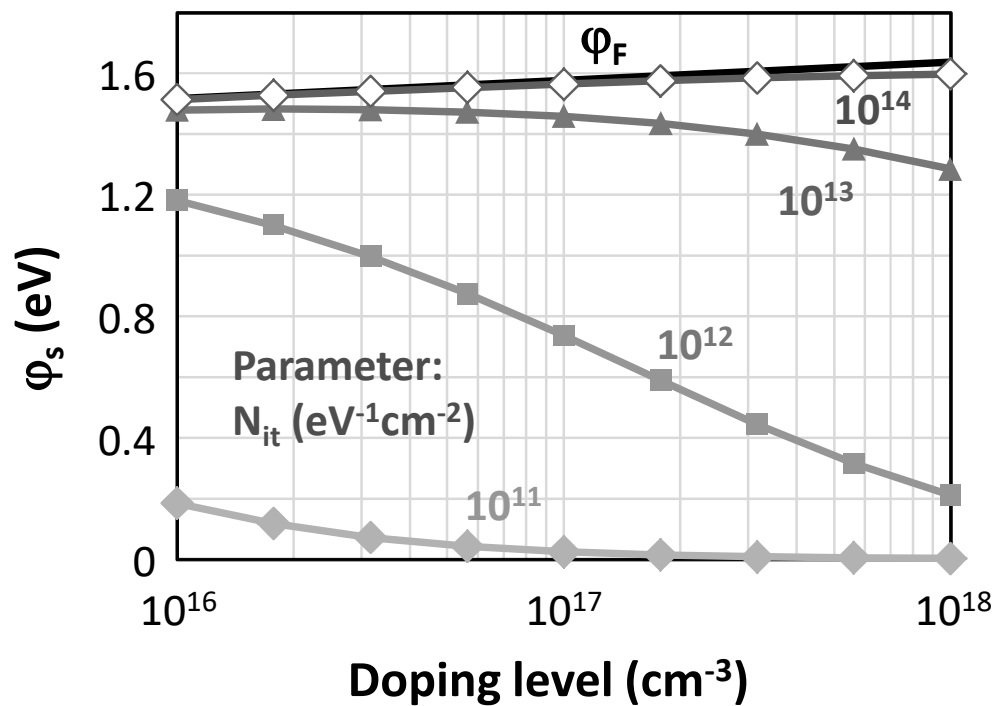
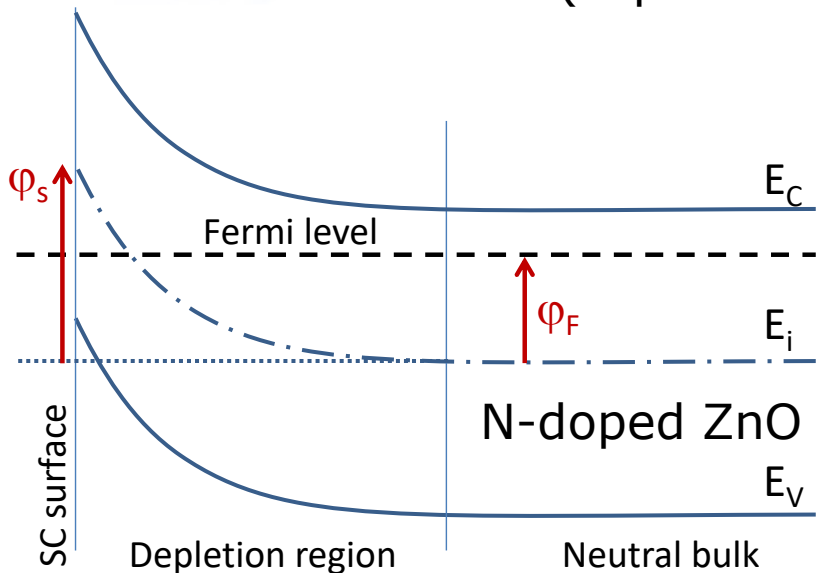


# **Surface traps** **Influence in VING performance**



# Origin of Surface Traps and their consequences

**Surface Traps** : e. g. in ZnO, presence of O<sub>2</sub> molecules at the surface (capture free electrons), surrounding material...



**SFLP: Surface Fermi Level Pinning**

- For a high density of traps ( $N_{it}$ ):  $\phi_s = \phi_F$  → SFL pinned at mid-gap
- **Hypothesis** :  $N_{it} \sim 5 \times 10^{11} \text{ cm}^{-2}\text{eV}^{-1}$  (medium range)

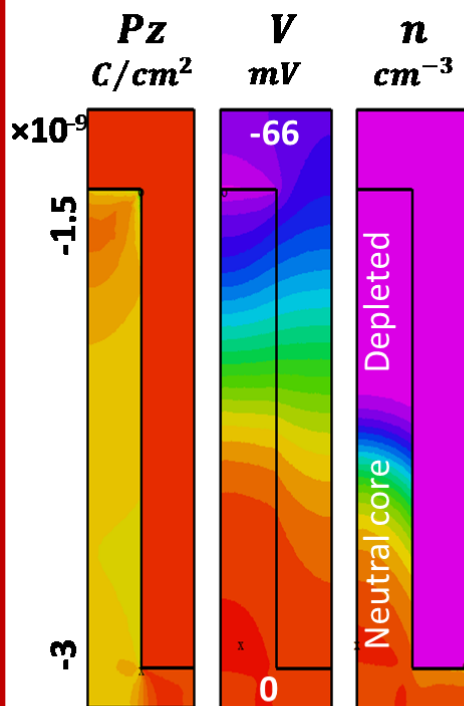
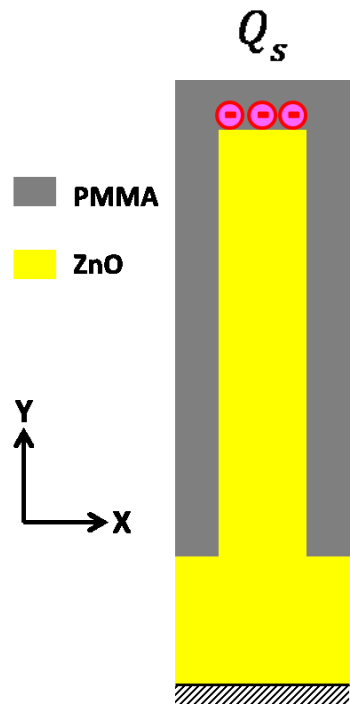
$$Q_{dep} = \sqrt{2q\epsilon N_D \phi_s} \quad \rightarrow \quad Q_{dep} + Q_s = 0$$

# Influence of Surface Fermi Level Pinning (1/4)

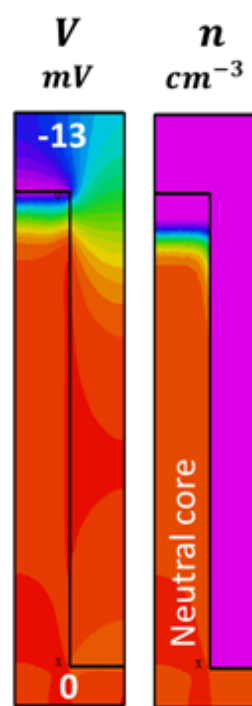
## SFLP on top vs. Doping (slow traps)

$P = 1\text{MPa}$   $R = 100\text{nm}$   $L = 600\text{nm}$

Unit cell :  
SFLP on top



Low doping level  
 $N_D = 10^{16} cm^{-3}$



Medium doping level  
 $N_D = 10^{17} cm^{-3}$



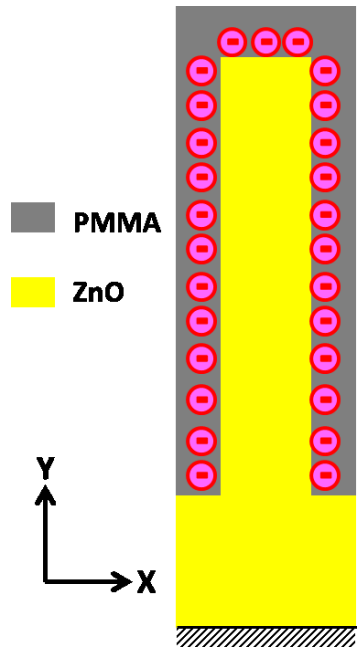
High doping level  
 $N_D = 10^{18} cm^{-3}$

- Depleted from the top, depending on doping level
- Allows much higher doping level to be used

# Influence of Surface Fermi Level Pinning (2/4)

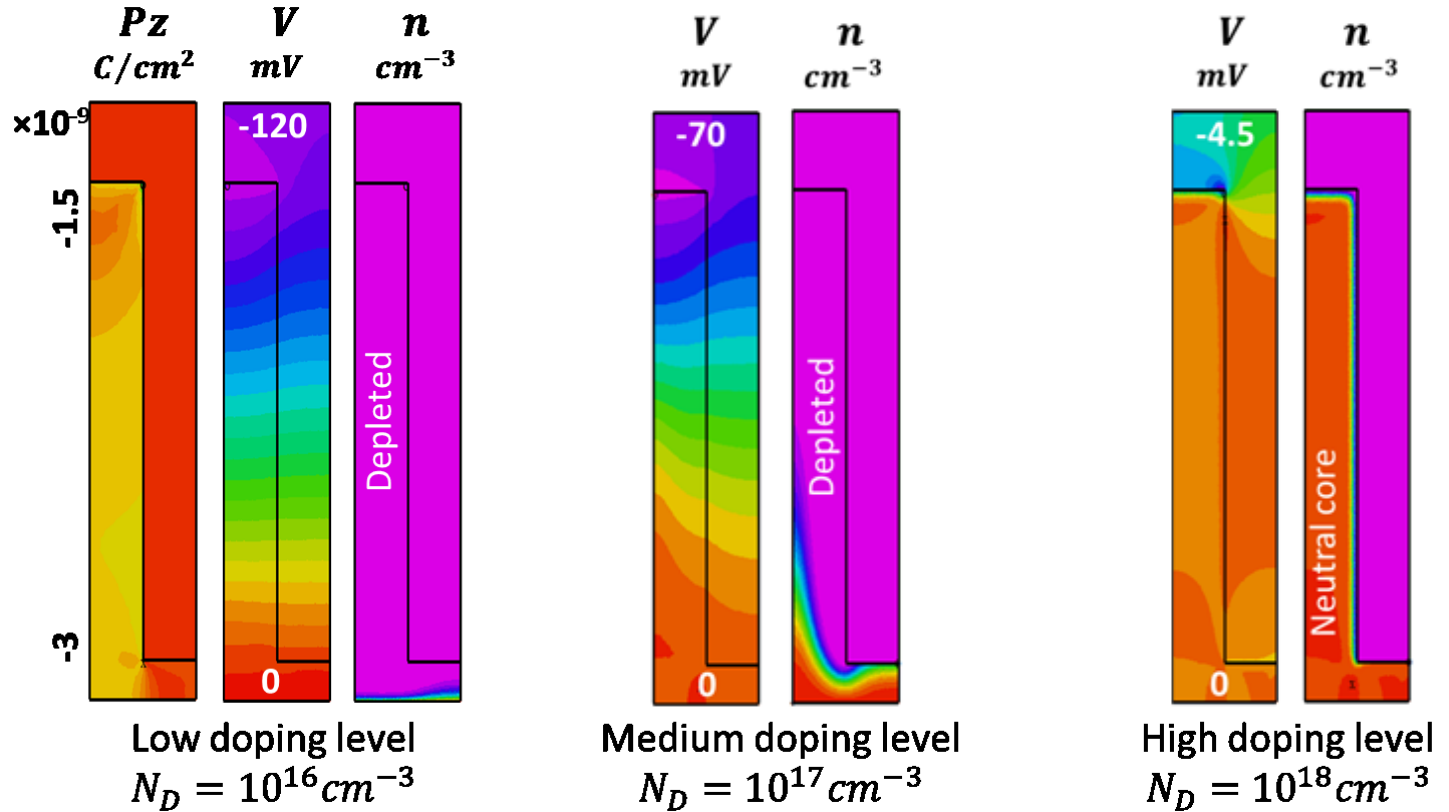
## SFLP at all interfaces vs. Doping (slow traps)

Unit cell :  
SFLP on all  
surfaces



Bottom:  
grounded and  
constrained

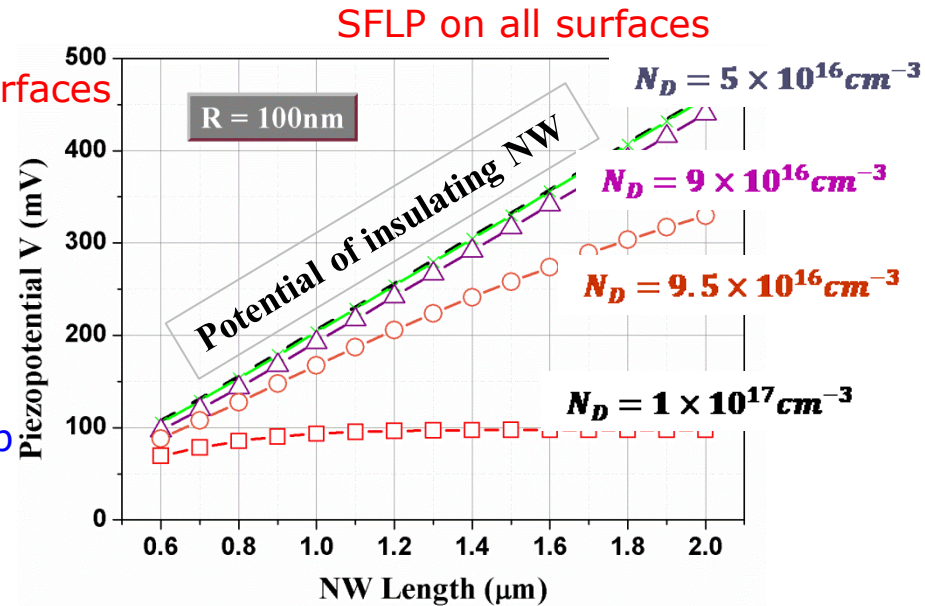
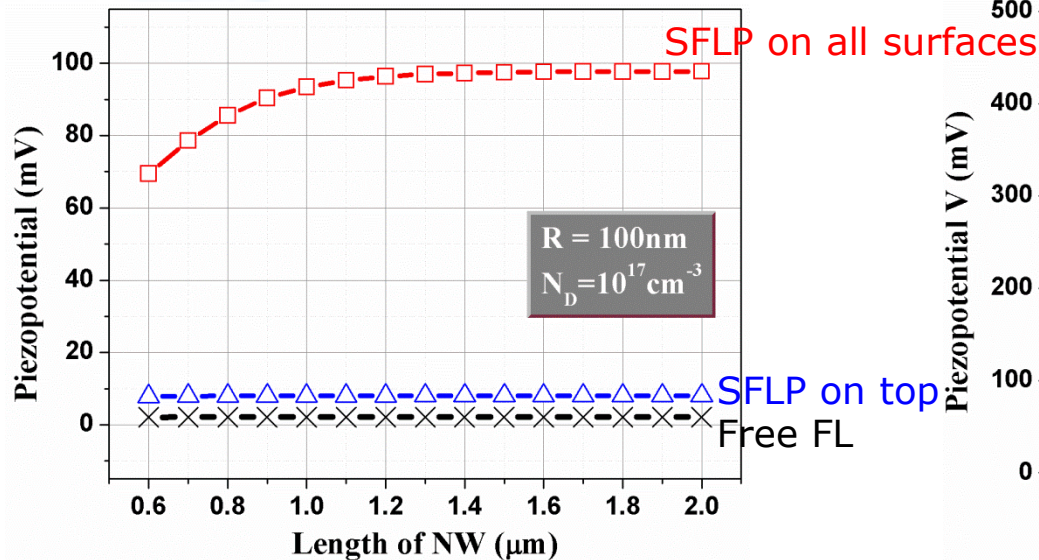
$P = 1\text{MPa}$   $R = 100\text{nm}$   $L = 600\text{nm}$



- Depleted from all sides, depending on doping level
- Fully depleted at low doping and start to form neutral core at medium doping
- Allows much higher doping level to be used

# Influence of Surface Fermi Level Pinning (3/4)

## Effect of NW length



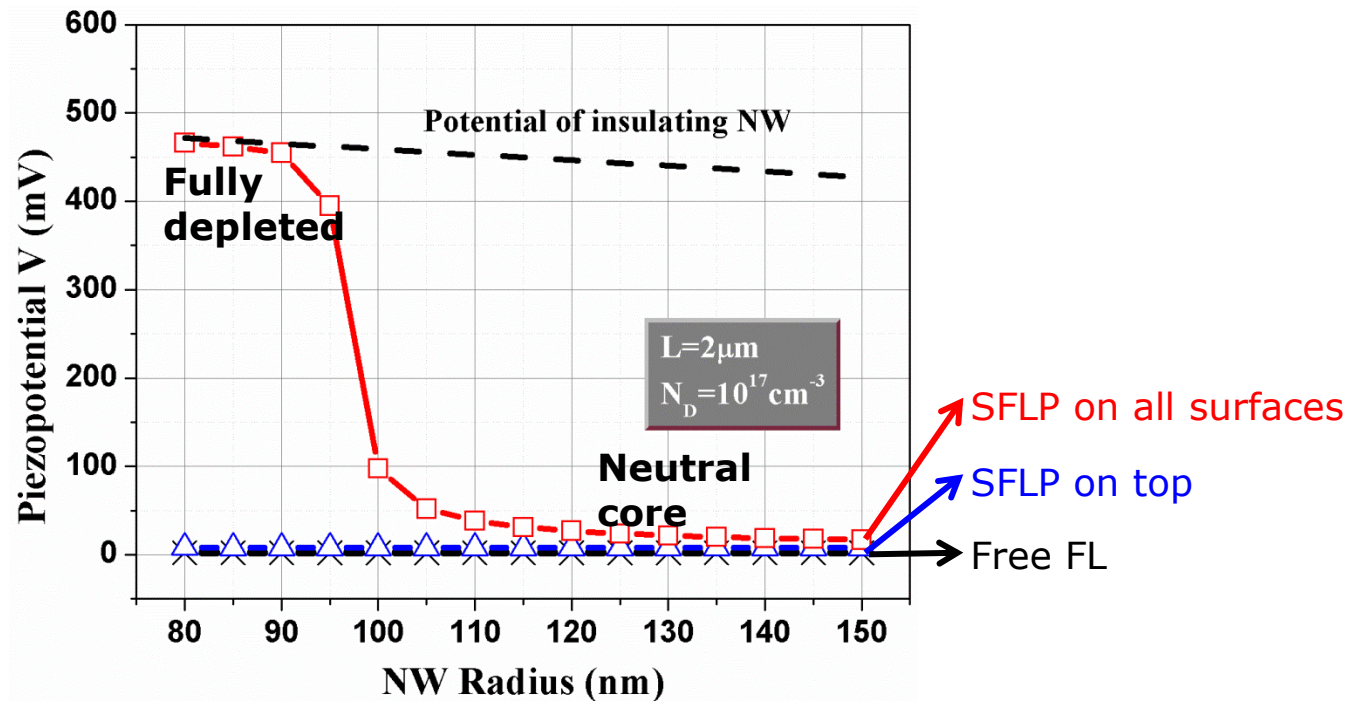
With free FL and SFLP on top only,

VING response is length-independent, consistent with Romano *et al.*

With SFLP at all interfaces,

VING response increases with length, length-dependency proved  
It becomes interesting to increase NW length (as for piezoelectric insulators)





With free FL and SFLP on top only,

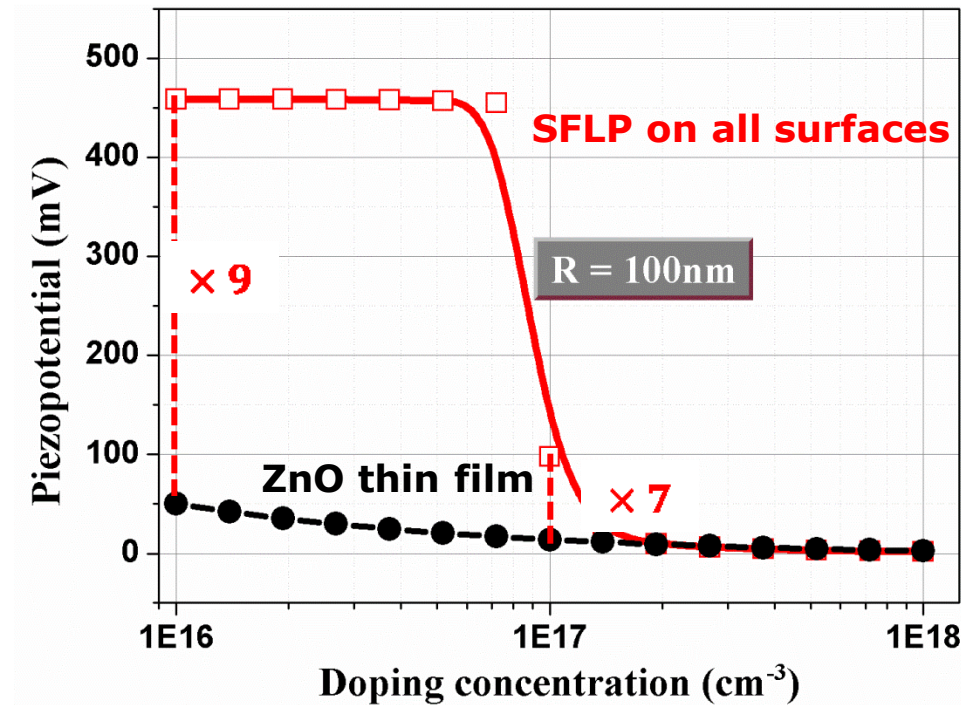
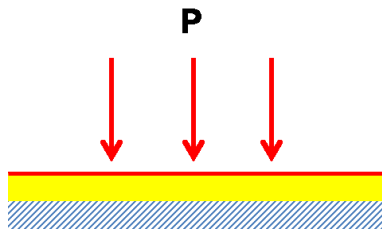
- VING response is radius-independent

With SFLP on all interfaces,

- VING response increases with the decrease of NW radius, radius-dependency
- It becomes interesting to use thinner NW

# NG cell vs thin film Under compression

Thin film thickness:  $2\mu\text{m}$     NW length:  $2\mu\text{m}$     Doping level varied

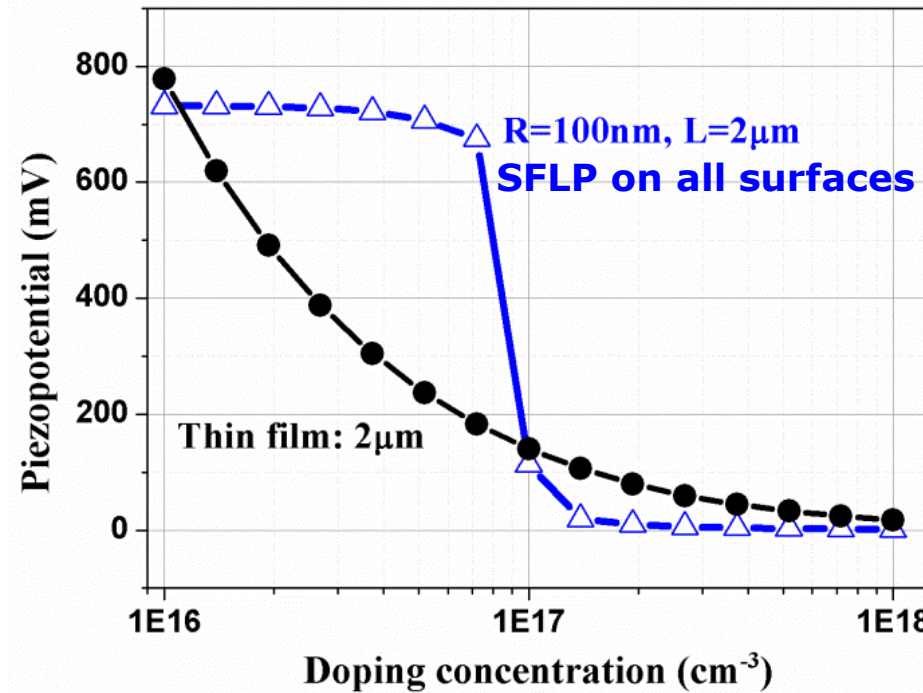
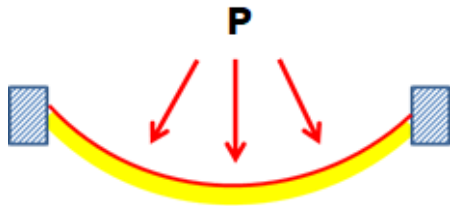


Compared with a ZnO thin film,

- Output of VING is higher than the thin film
- 6 times improved at medium doping level

# NG cell vs thin film Under bending

Thin film thickness:  $2\mu\text{m}$     NW length:  $2\mu\text{m}$     Doping level varied



Compared with a ZnO thin film,

- Similar maximum output
- Higher range of exploitable doping levels with NG



- **Piezo nanowires and nanocomposites are promising for mechanical energy harvesting and sensing**
- **SFLP could explain the high performance reported in experiments**
- **Important optimization guidelines :**
  - VING (**composite**) performance depends on the NWs length and radius
  - It is better to use long and thin NWs
- **Piezoelectric composite based on semiconducting NWs could outperform piezo thin films**

- **AFM characterization methods : combination of mechanical and electrical modes**
- **Studies of performance in function of traps densities, traps dynamics (slow and fast traps)**
- **Studies of the influence of traps to other devices based on piezoelectric semiconducting materials.**
- **Validation of the models through experiments**





# Thank you for your attention...

## Acknowledgements:

- **PhD. Students:** A. Lopez, R. Hinchet, R. Tao, X. Xu, A. Potié
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- **Clean Room staff:**
  - A. Bouchard (IMEP-LaHC)
  - PTA and CIME
- **Collaborators:** Prof. Z. L. Wang (GeorgiaTech/BINN), R. Songmuang (I. Néel), E. Paulliac-Vaujour (CEA-Leti), S. Monfray (STMicroelectronics), J. Penuelas (INL), B. Salem (LTM), V. Consonni (LMGP)
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